

Title (en)

A METHOD FOR FABRICATING NANOGAP AND NANOGAP SENSOR

Title (de)

VERFAHREN ZUR ERZEUGUNG EINES NANOSPALTS UND NANOSPALTSSENSOR

Title (fr)

PROCEDE POUR FABRIQUER UN NANO-INTERVALLE ET CAPTEUR DE NANO-INTERVALLE

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Abstract (en)

[origin: WO2007046582A1] The present invention relates to a method of fabricating a nanogap and a nanogap sensor, and to a nanogap and a nanogap sensor fabricated using the method. The present invention relates to a method of fabricating a nanogap and a nanogap sensor, which can be realized by an anisotropic etching using a semiconductor manufacturing process. According to the method of present invention, the nanogap and nanogap sensor can be simply and cheaply produced in large quantities.

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